

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Narwankar et al.

Application No.: 10/772,893

Filed: February 4, 2004

For: TAILORING NITROGEN PROFILE
IN SILICON OXYNITRIDE USING
RAPID THERMAL ANNEALING WITH
AMMONIA UNDER ULTRA-LOW
PRESSURE

Examiner: Kelly M Stouffer

Art Unit: 1792

Confirmation No.: 5371

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT UNDER 37 CFR §1.111

Dear Examiner:

This is in response to the Office Action mailed June 17, 2008. Applicants respectfully request the Examiner to enter this Amendment and consider the following remarks.

The Listing of Claims begins on page 2 of this paper.

Remarks/Arguments begin on page 11 of this paper.

I hereby certify that this correspondence is being deposited via
EFS Web on the date below:

September 17, 2008

Date of Deposit

/Justin K. Brask/

Justin K. Brask, Reg. #61,080